

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

1/22

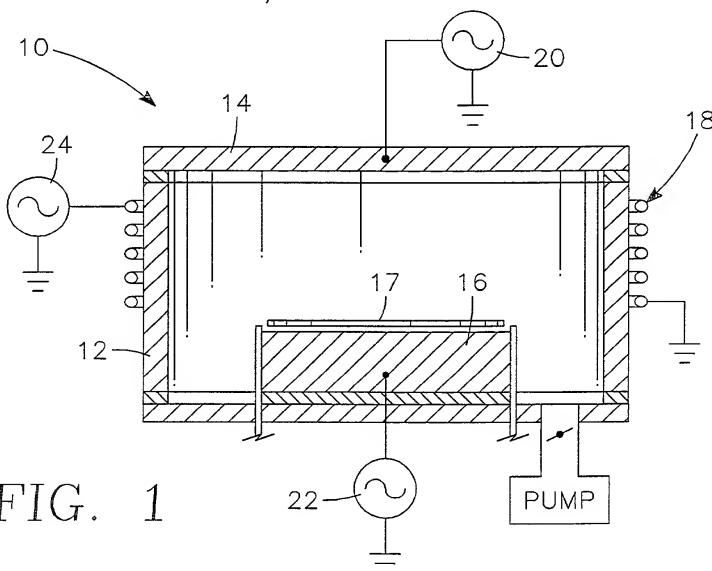


FIG. 1

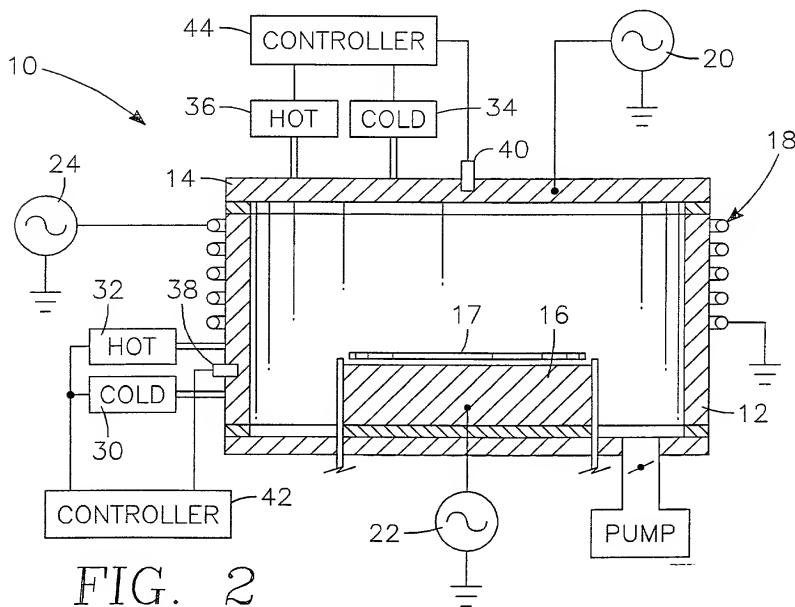


FIG. 2

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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 CO9

2/22

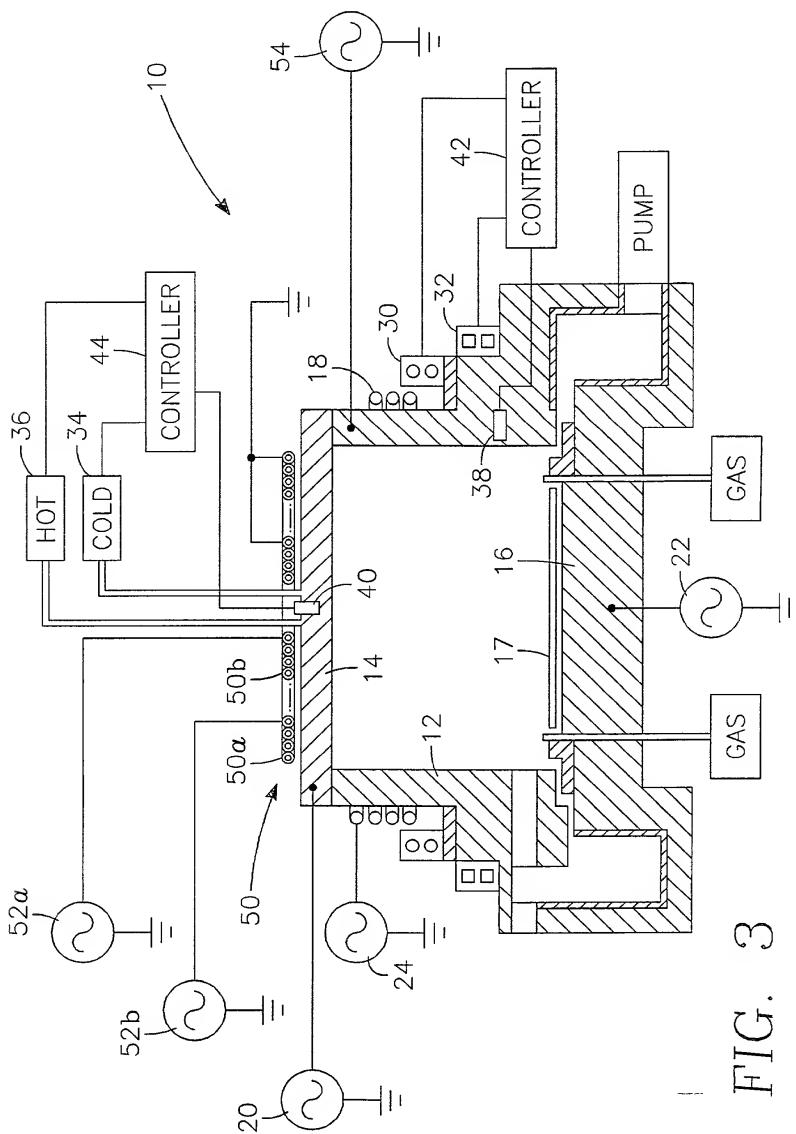
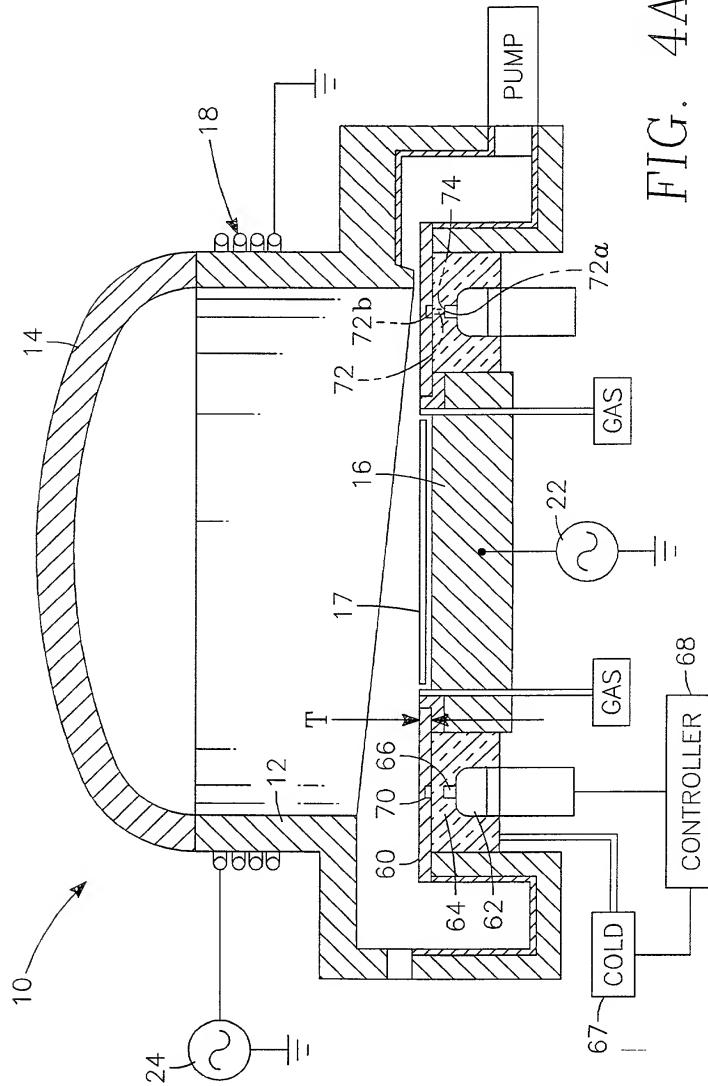


FIG. 3

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
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ATTORNEY DOCKET 306 C09

3/22

FIG. 4A



LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
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ATTORNEY DOCKET 306 C09

4/22

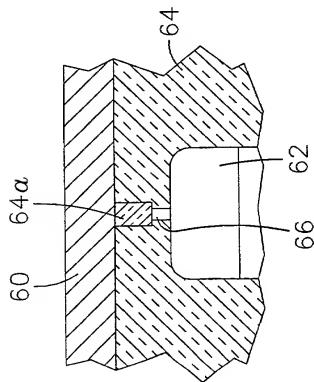


FIG. 4D

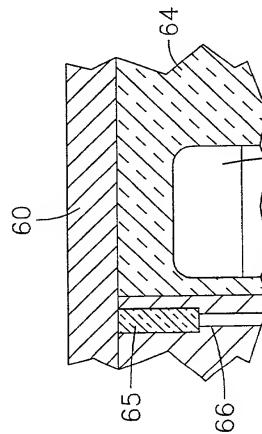


FIG. 4E

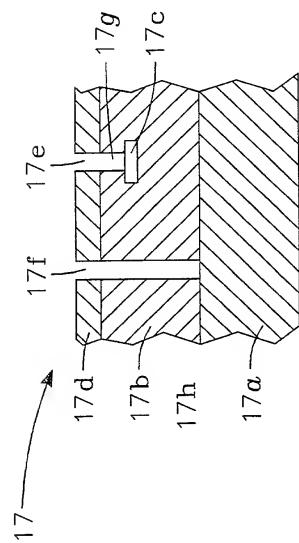


FIG. 4B

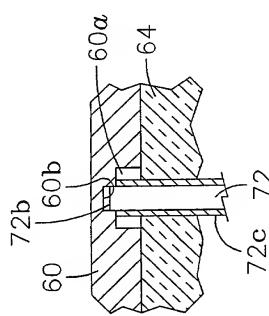


FIG. 4C

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
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ATTORNEY DOCKET 306 C09

5/22

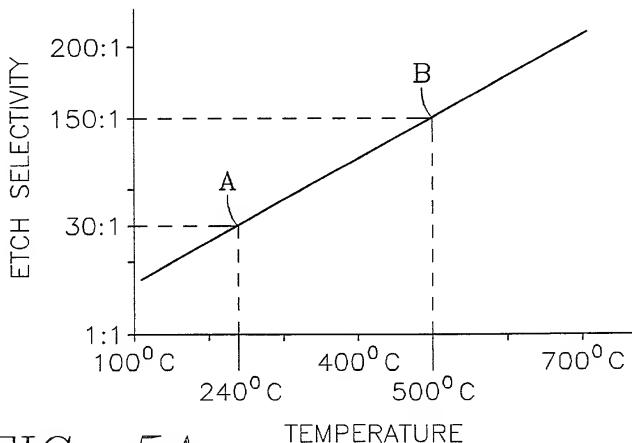


FIG. 5A

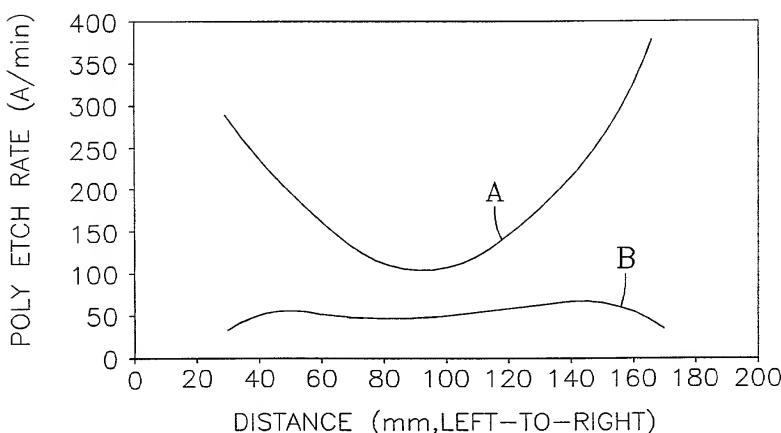
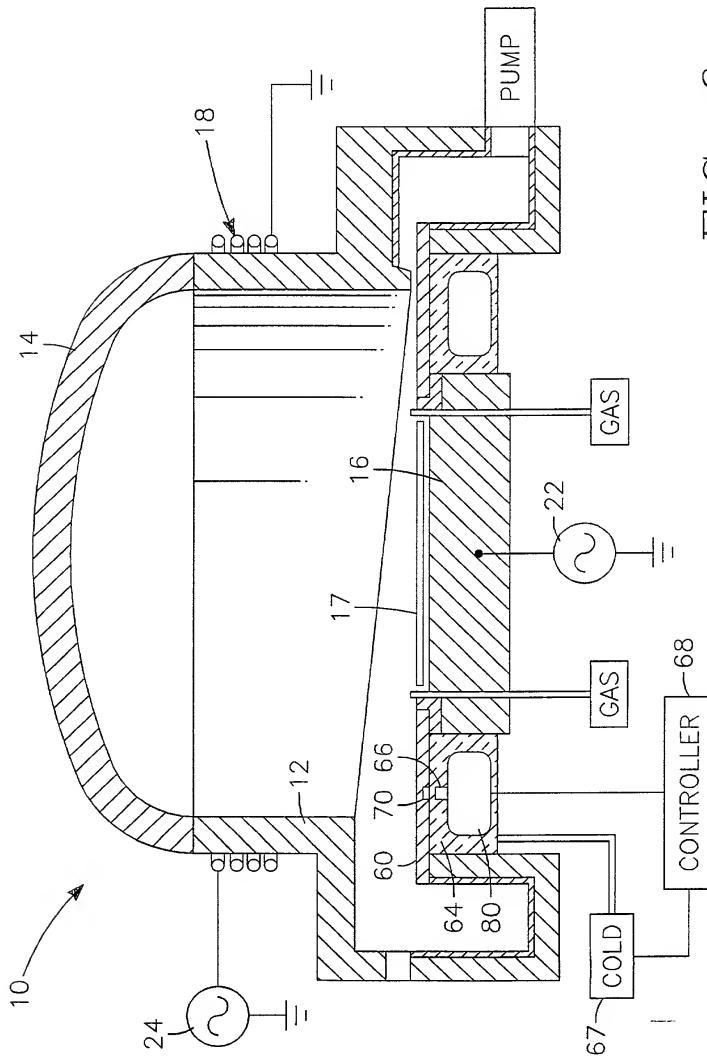


FIG. 5B

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
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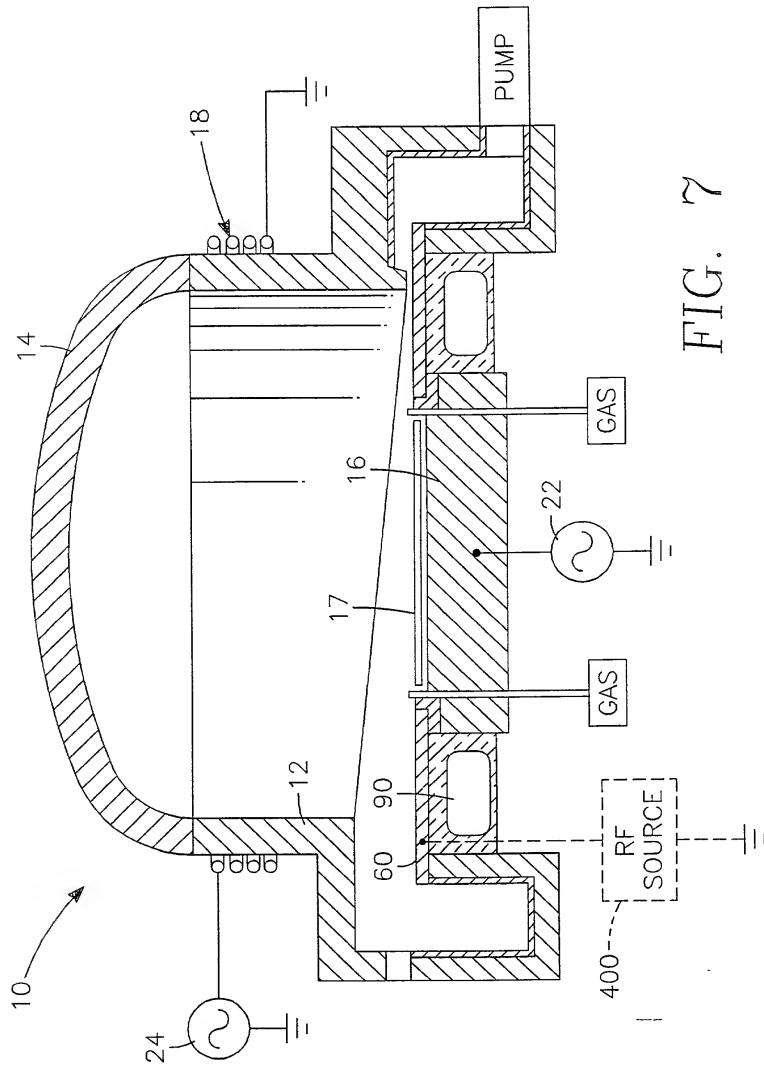
6/22

FIG. 6



LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

7/22



7

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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

8/22

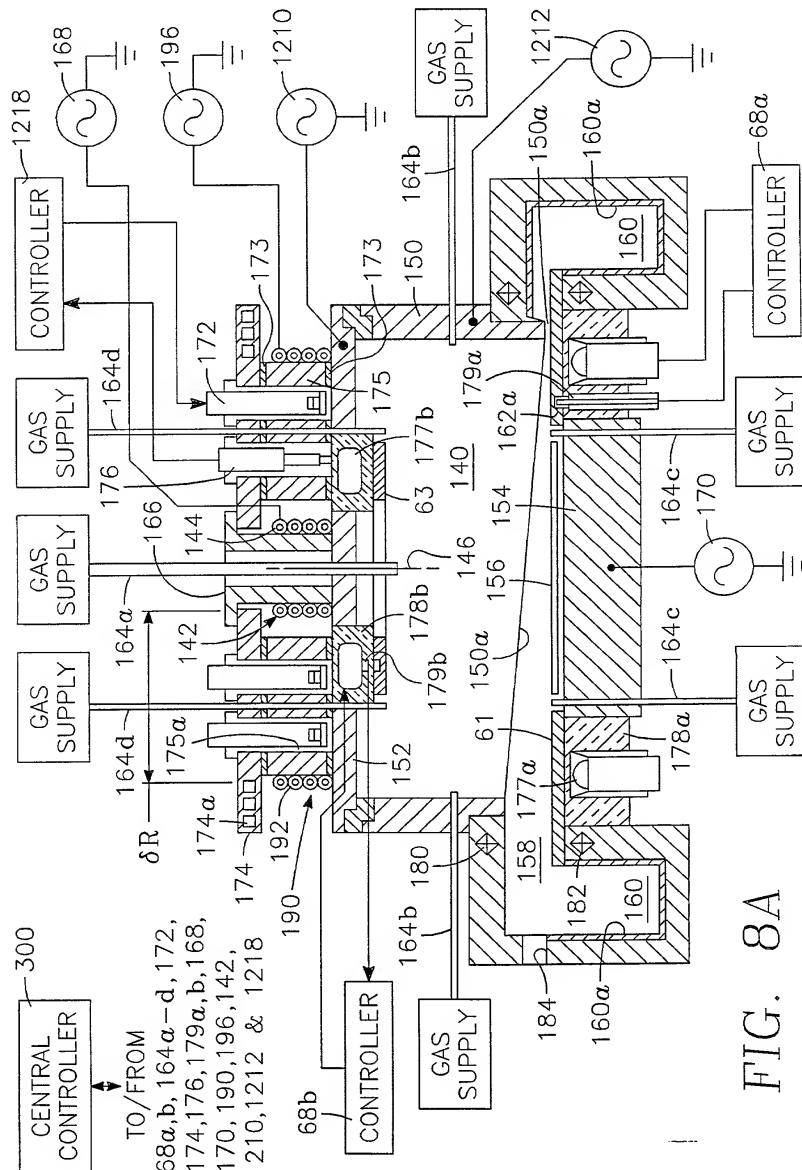
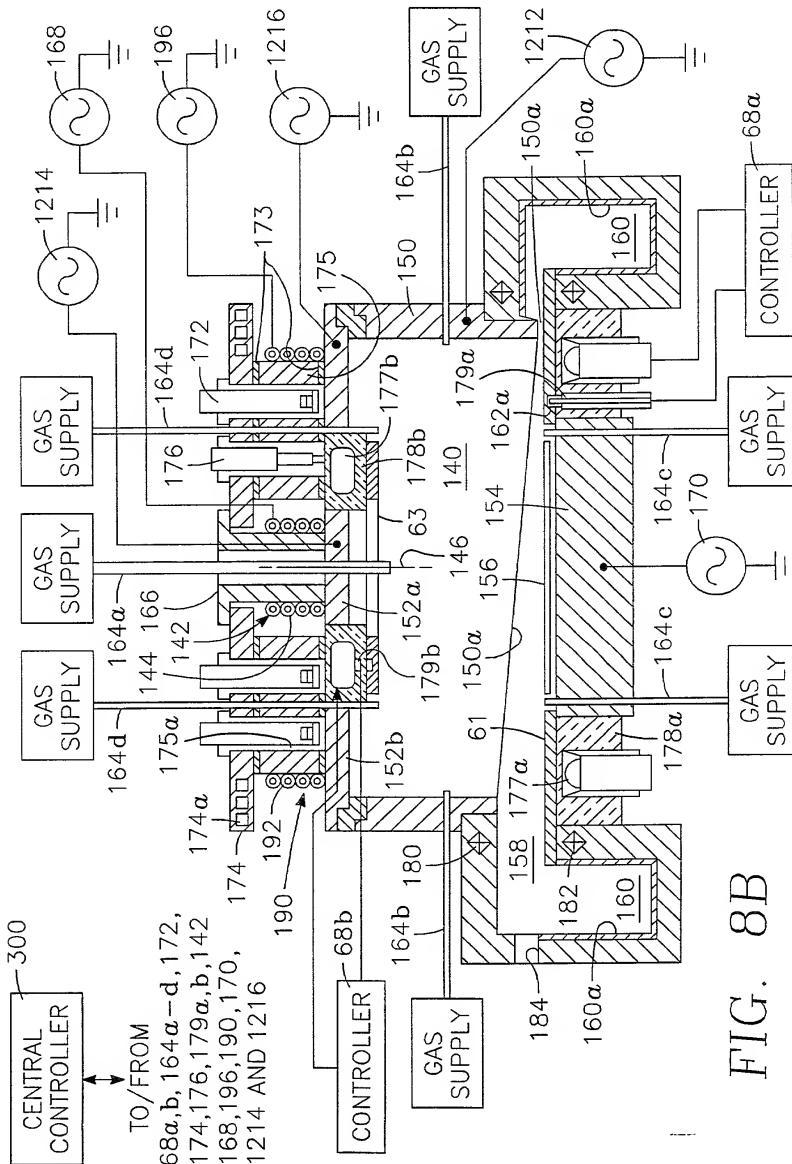


FIG. 8A

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
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ATTORNEY DOCKET 306 C09

9/22



LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 CO9

10/22

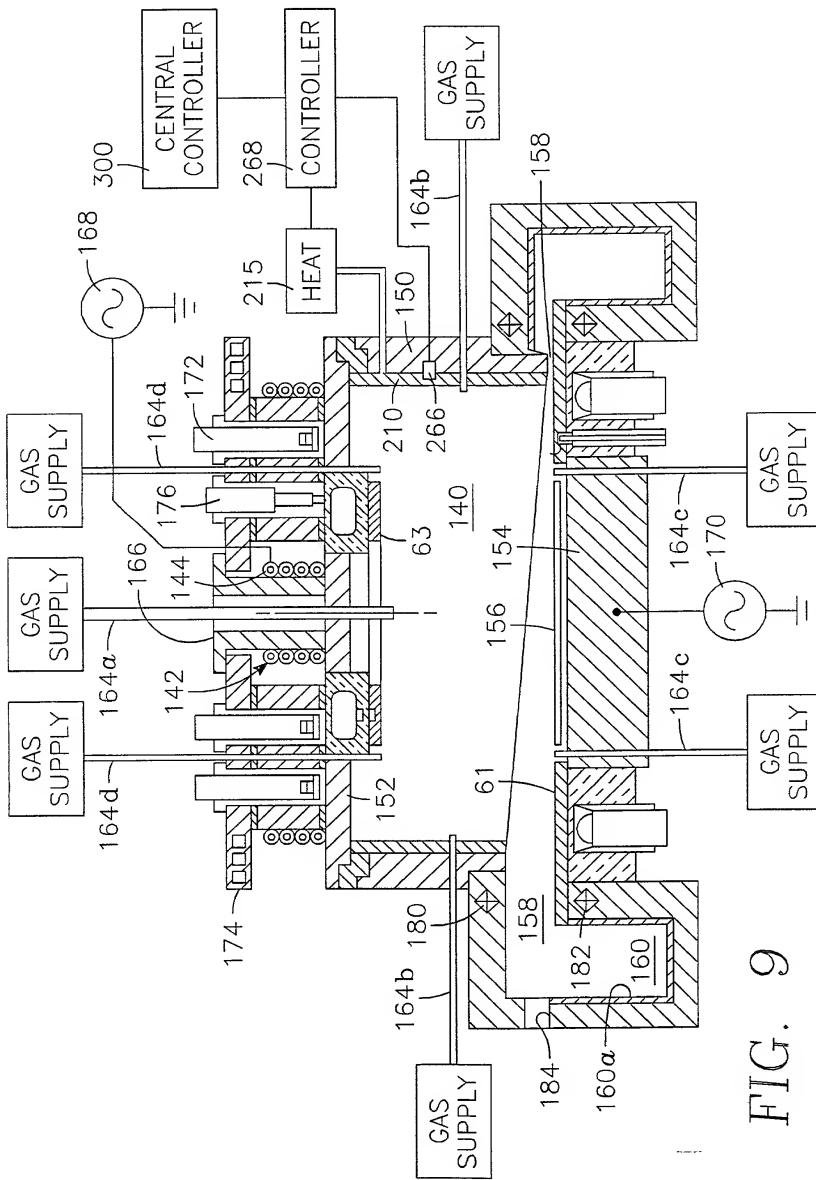


FIG. 9

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
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ATTORNEY DOCKET 306 C09

11/22

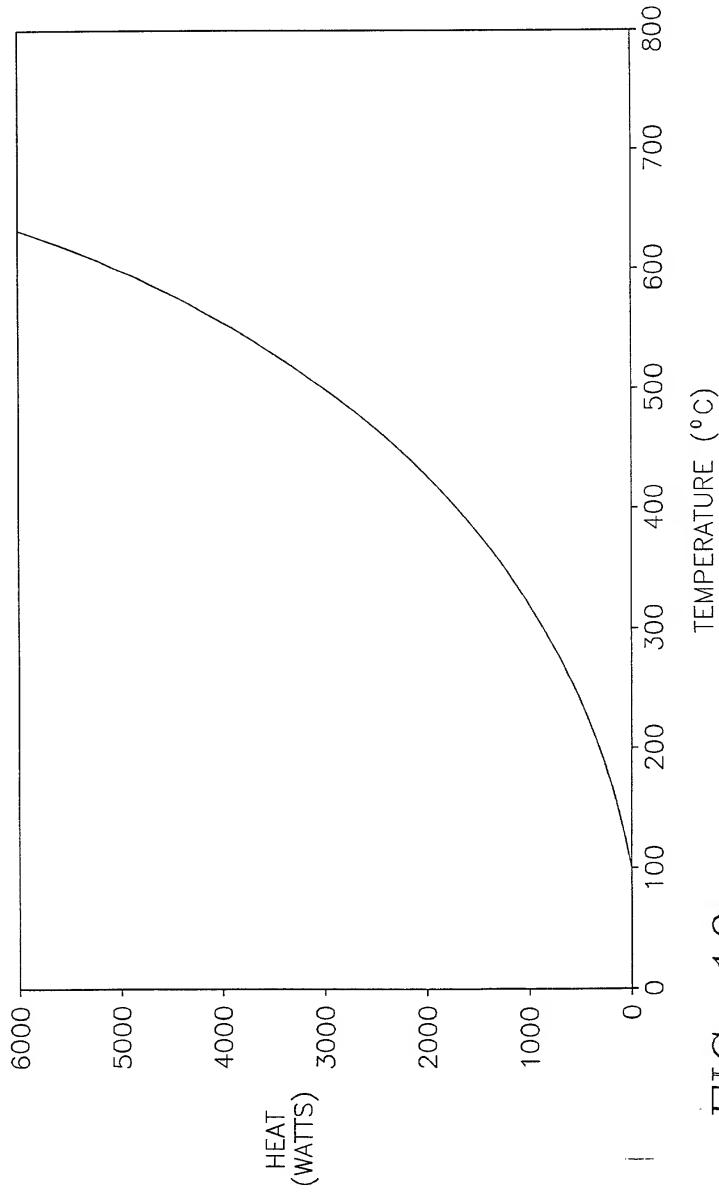
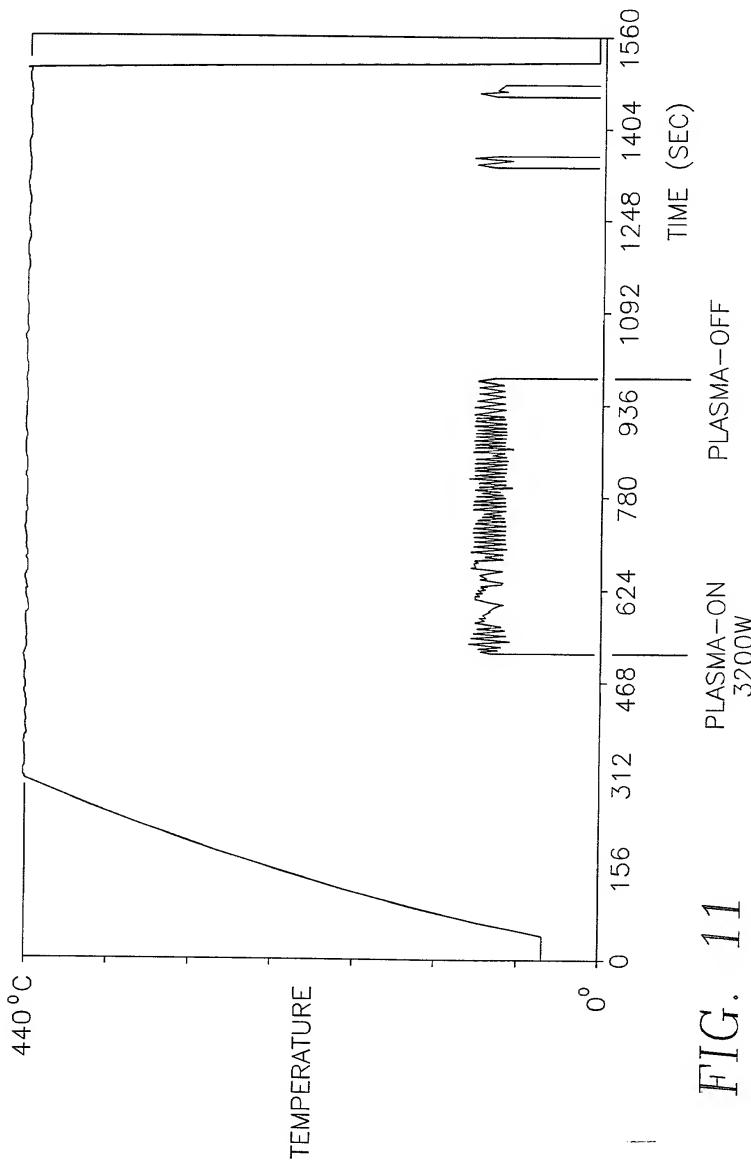


FIG. 10

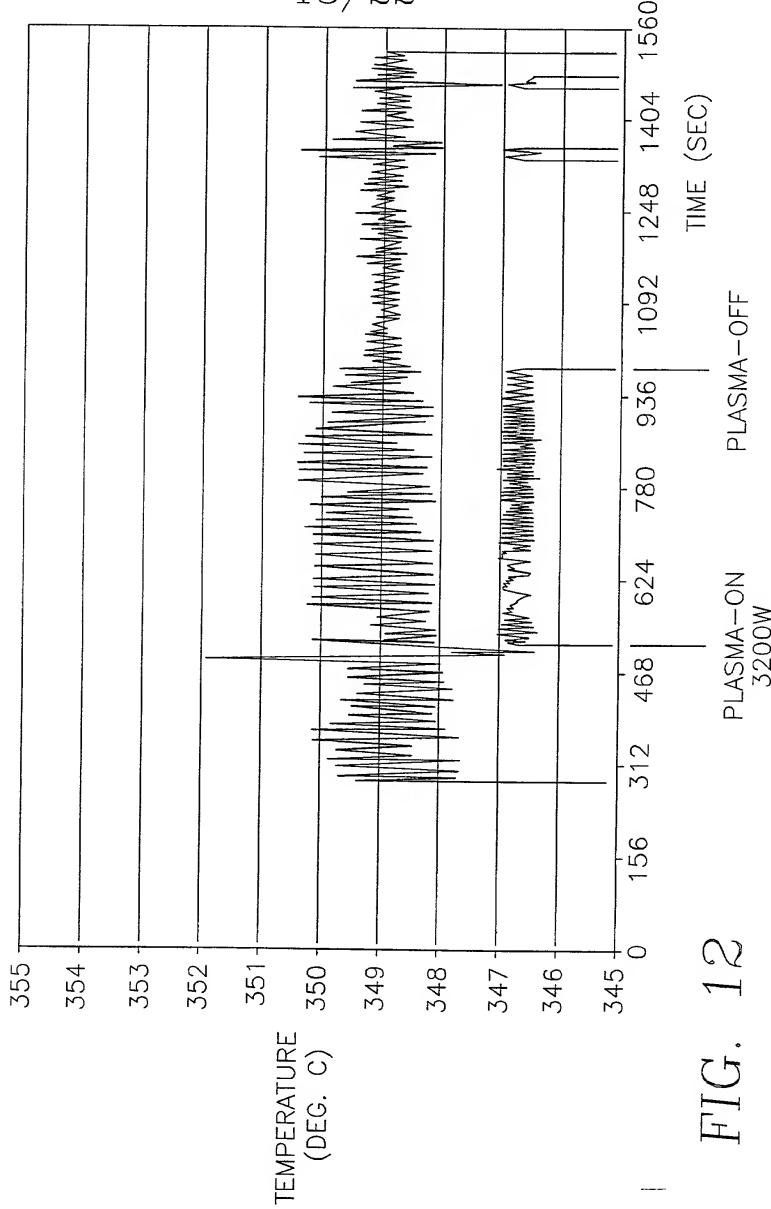
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ATTORNEY DOCKET 306 C09

12/22



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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

13/22



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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

14/22

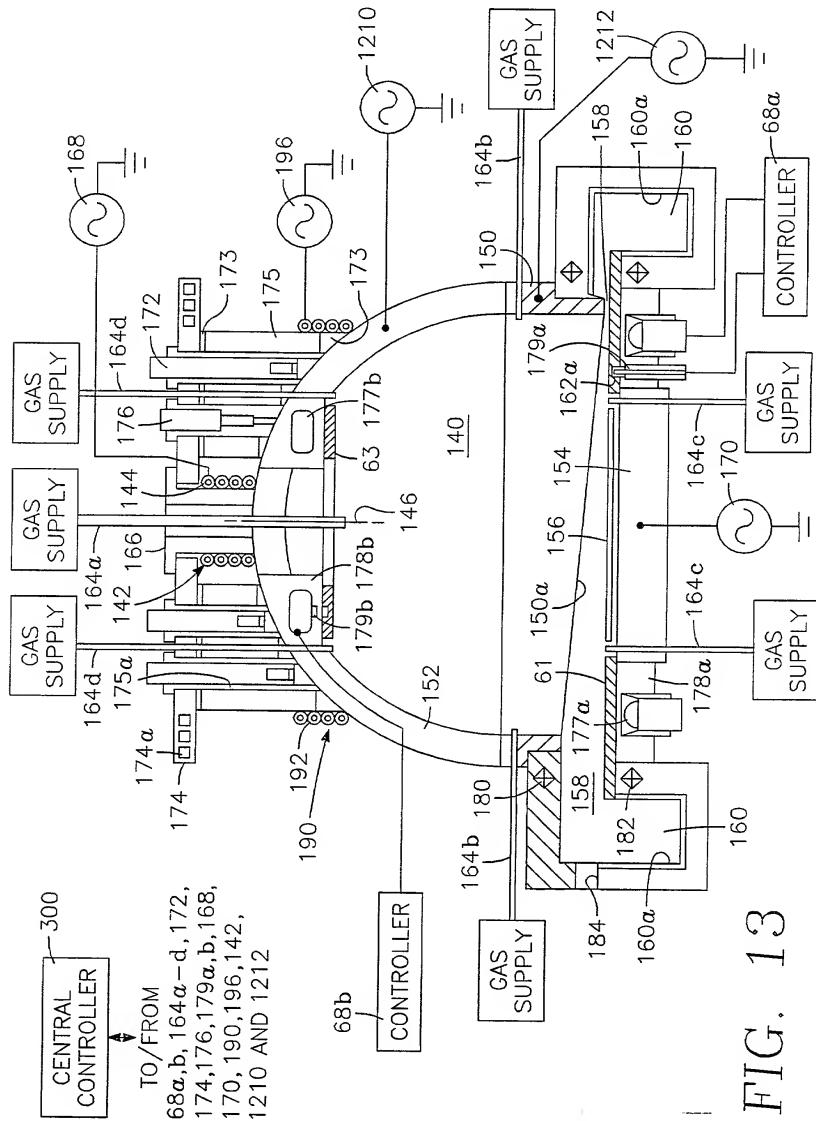
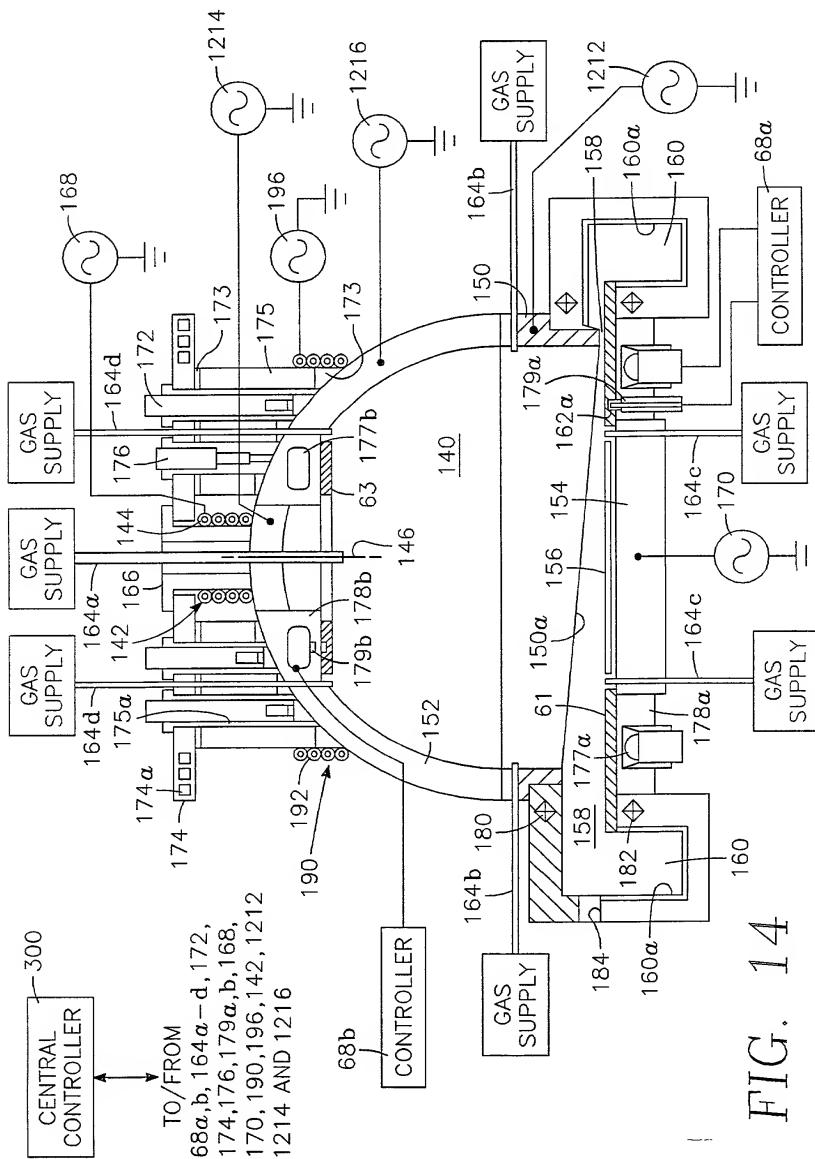


FIG. 13

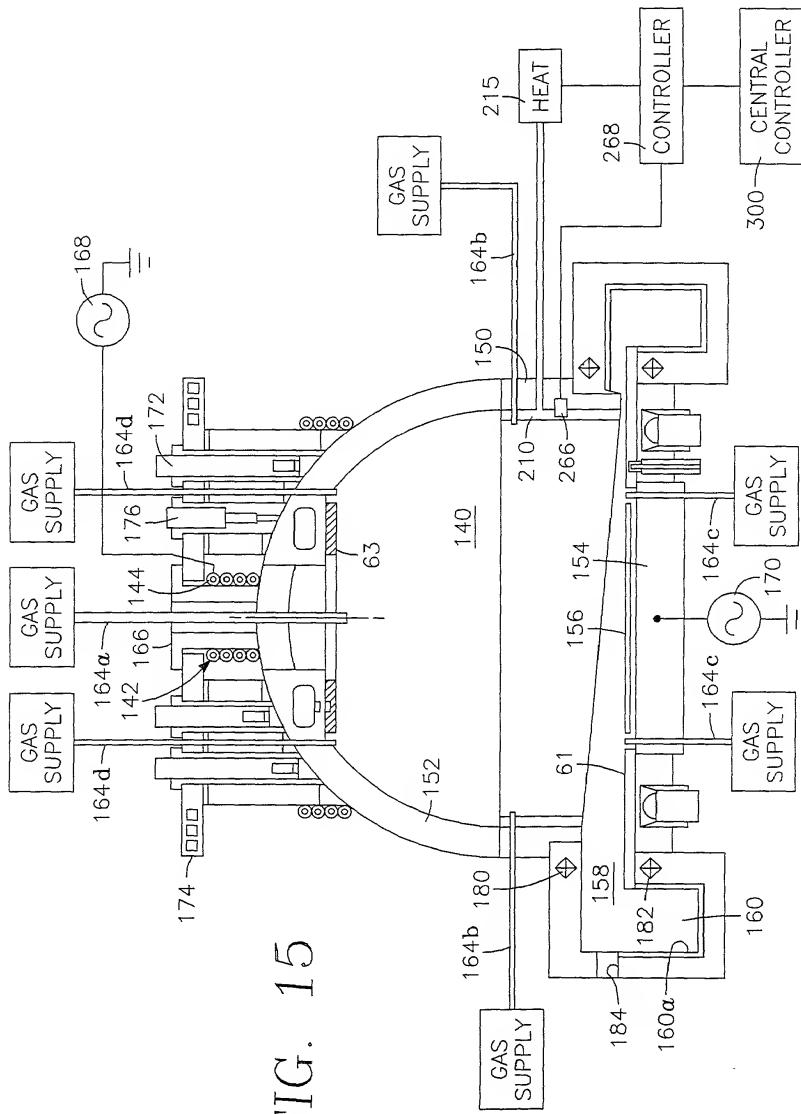
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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

15/22



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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

16/22



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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

17/22

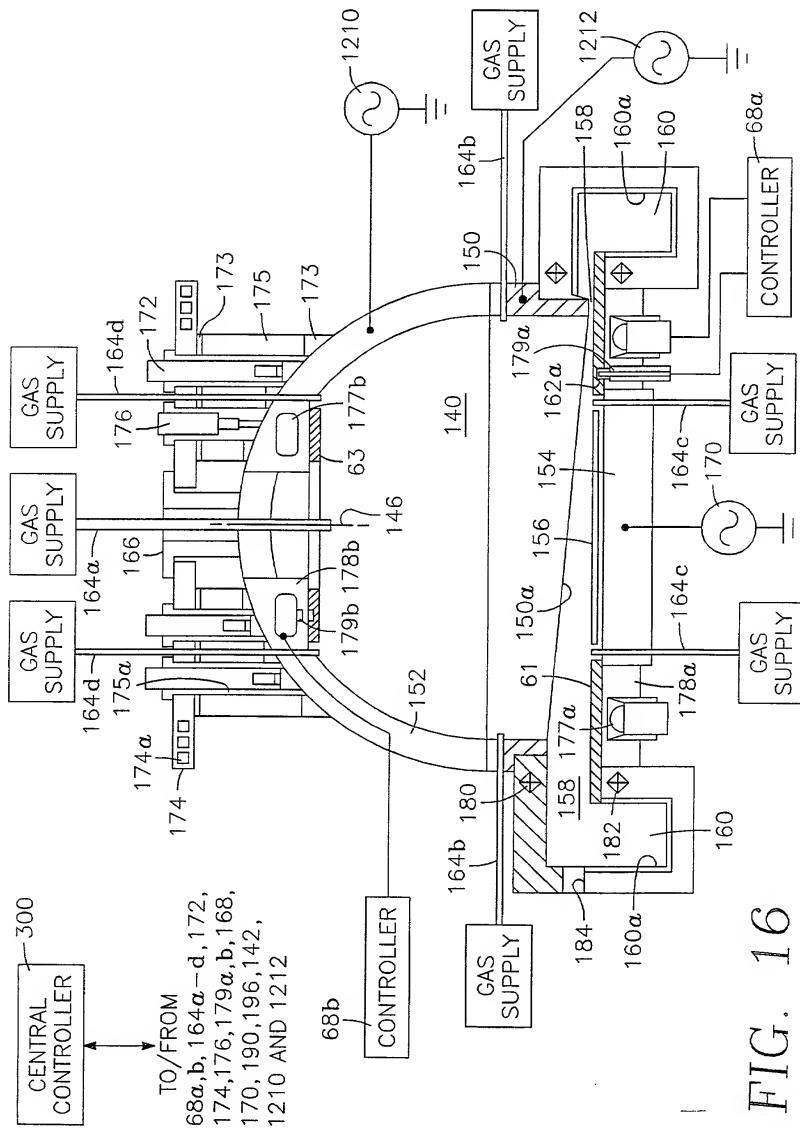
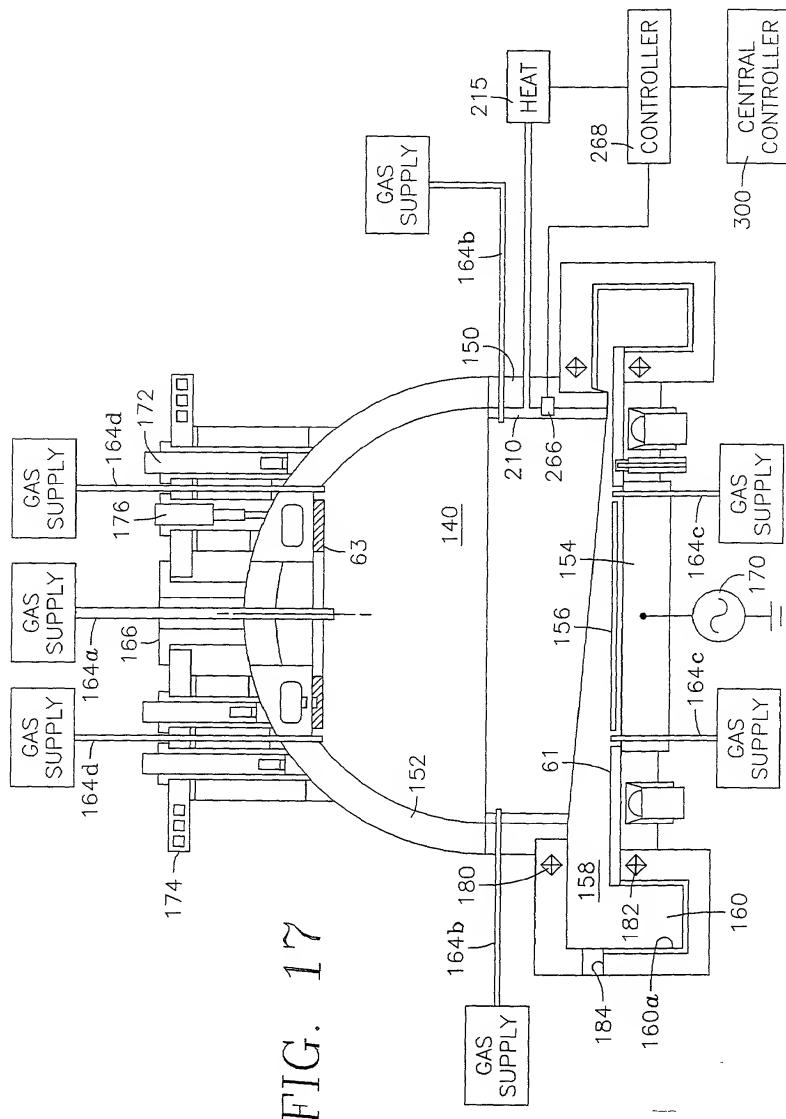


FIG. 16

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

18/22



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HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 CO9

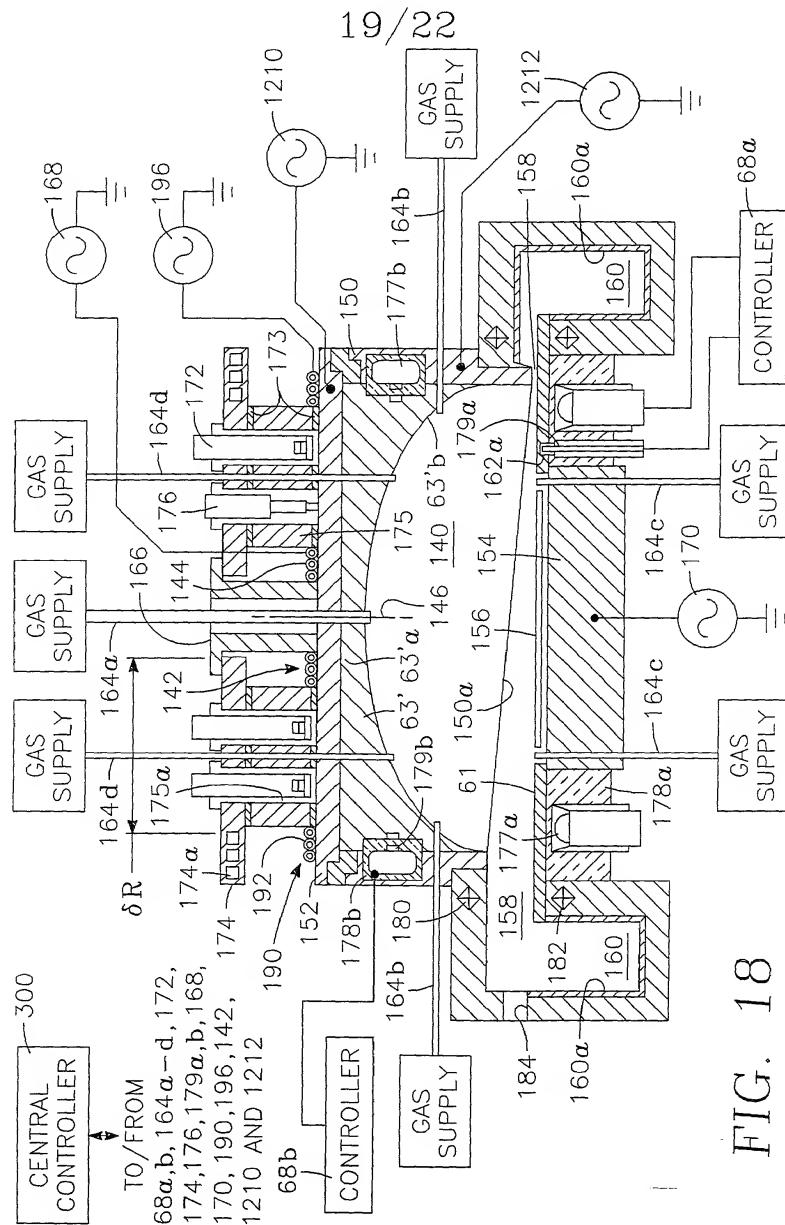


FIG. 18

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

20/22

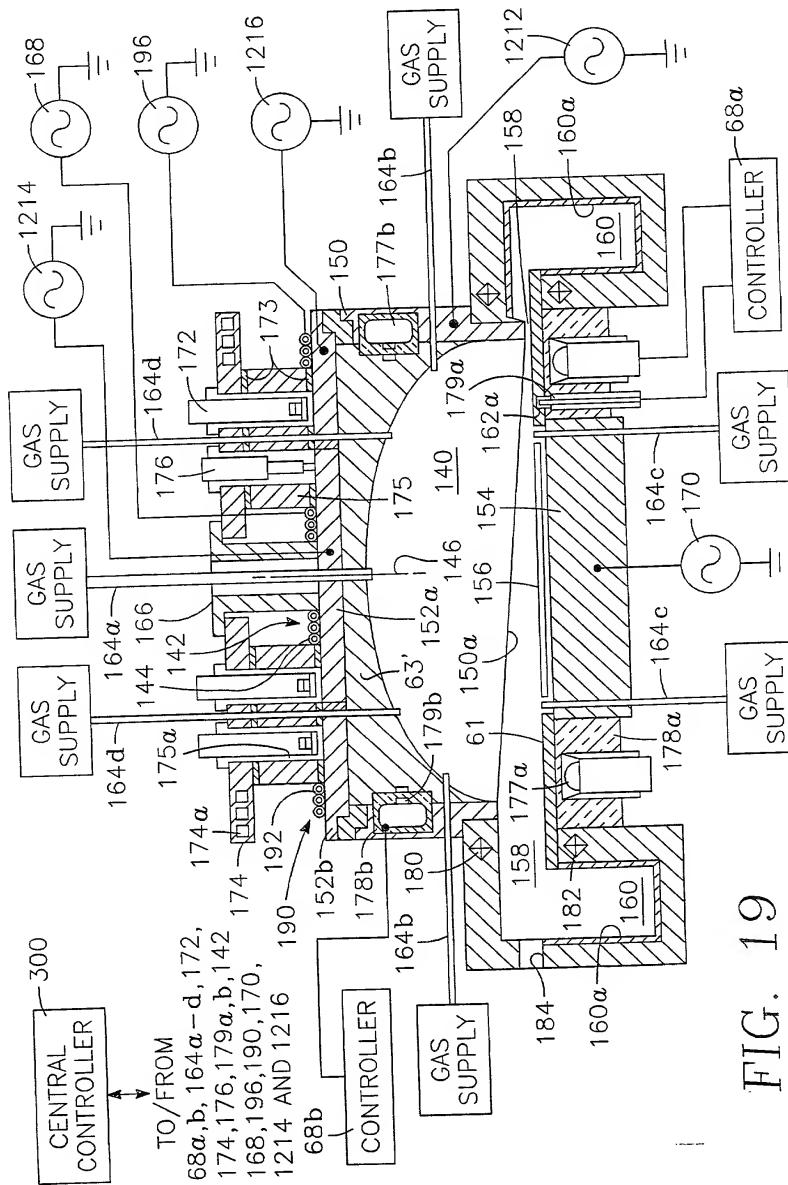


FIG. 19

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 C09

21/22

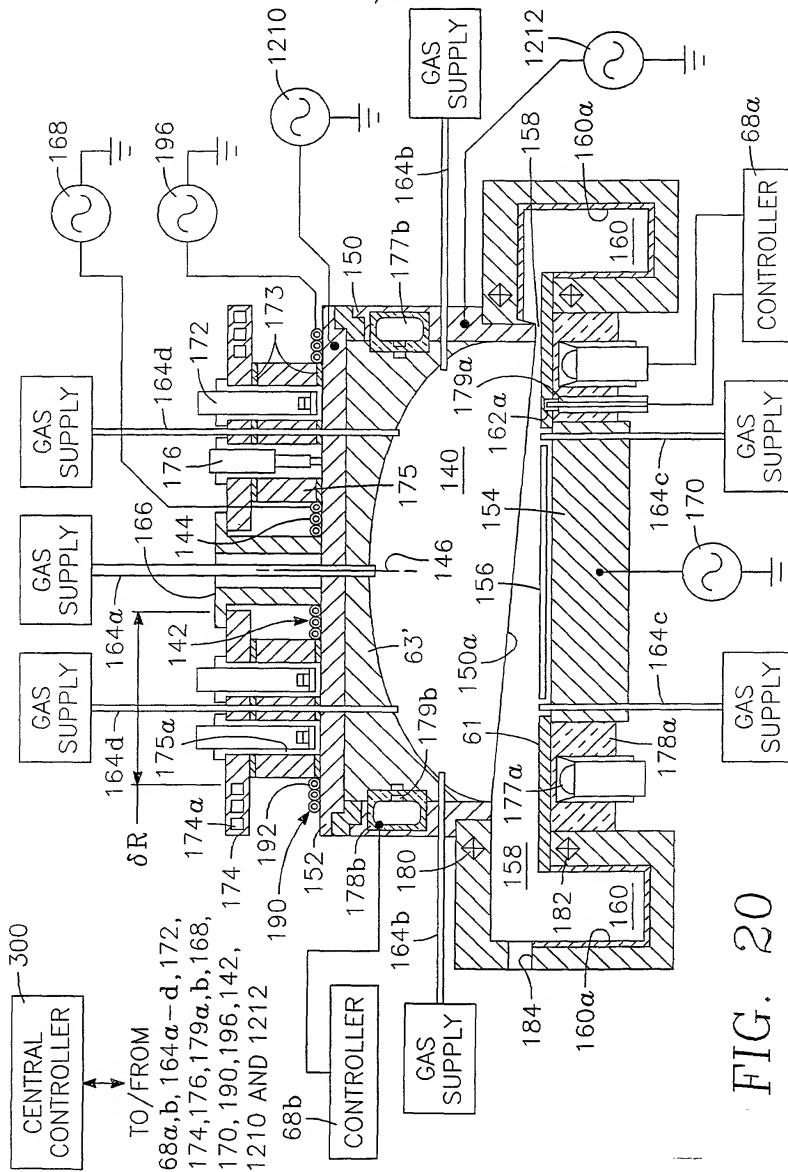


FIG. 20

LOW CEILING TEMPERATURE PROCESS FOR A PLASMA REACTOR WITH  
HEATED SOURCE OF A POLYMER-HARDENING PRECURSOR MATERIAL  
ATTORNEY DOCKET 306 CO9

22/22

